

Sheet 1 of 1

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| Form PTO-1449 (REV. 8-83) | | US Dept. of Commerce PATENT & TRADEMARK OFFICE | | ATTY DOCKET NO. 109325.01 | | APPLICATION NO. 10/791,810 | |
| INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary) | | | | APPLICANT(S) Yuji IMAI | | | |
| | | | | FILING DATE March 4, 2004 | | GROUP 2851 | |
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| EXAMINER H. Nguyen | | | | DATE CONSIDERED 1/15/05 | | | |
| Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. | | | | | | | |

Date: December 1, 2004